



Appl. No. 10/077,072
Amtd. dated 11/7/2003
Reply to Office action of 09/09/2003

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of:)
FISCHER et al.) Group Art Unit: 2821
Application No: 10/077,072) Examiner: LEE, Wilson
Filed: February 14, 2002) Atty. Docket No: P0877
For: A PLASMA PROCESSING APPARATUS) Date: November 7, 2003
AND METHOD FOR CONFINING AN RF)
PLASMA UNDER VERY HIGH GAS FLOW)
AND RF POWER DENSITY CONDITIONS)

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on November 7, 2003.

Signed: Sharon Tillery
Sharon Tillery

*Approved
to be entered
MS 1-20-04*
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

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Dear Sir:

In response to the Office Action mailed on September 9, 2003, please enter the following amendments and remarks in the above-identified patent application:

Amendments to the specifications begin on page 2.

Amendments to the claims are reflected in the listing of claims, which begins on page 3 of this paper.

Remarks/Arguments begin on page 8 of this paper.